



Attorney Docket # 5367-47RCE2

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Stefan BADER et al.

Serial No.: 10/696,882

Filed: October 30, 2003

For: Method for Depositing a Material on a Substrate
Wafer

Examiner: RAO, G. Nagesh
Group Art: 1722

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Mail Stop RCE, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

October 22, 2007
(Date of Deposit)

Lance J. Lieberman
Name of applicant, assignee or Registered Representative

Signature

October 22, 2007
Date of Signature

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT UNDER 37 C.F.R. § 1.114

SIR:

PETITION

Applicants hereby petition for a one-month extension of the original shortened statutory response period set in the Final Office Action of June 21, 2007. The amount of \$120 in payment of the government fee for a one-month extension of time, so that the period for response is extended to October 21, 2007, is included herewith with the RCE filing fee. Any additional fees or charges required at this time in connection with the present application may be charged to our Patent and Trademark Office Deposit Account No. 03-2412.

RESPONSE

In conjunction with a Request for Continued Examination, this paper is in response to the to the Final Office Action dated June 21, 2007, please amend the above-identified application as follows:

Amendments to the Claims begin on page 3 of this paper.

Remarks begin on page 6 of this paper.